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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

TAKENO

Group Art Unit:

Serial No.: New Application

Examiner:

Filed: September 24, 2001

Docket No. P107242-00024

For: MANUFACTURING PROCESS FOR SILICON EPITAXIAL WAFER

PRELIMINARY AMENDMENT

Commissioner for Patents  
Washington, D.C. 20231

September 24, 2001

Sir:

Prior to calculation of the filing fee and prior to the examination of this application, please amend the above-identified application as follows:

IN THE TITLE:

Please amend the title to read MANUFACTURING PROCESS FOR

SILICON EPITAXIAL WAFER.

IN THE CLAIMS:

Please cancel original claims 1 through 5 and add the following claims:

-- 6. (Added) A manufacturing process for a silicon epitaxial wafer comprising the steps of:

A<sup>2</sup> 506